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CENTRAL FAX CENTER

005/036

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| FORM PTO-1449 (Modified) | ATTN: DOCKET NO. | SERIAL NO. |
| | 10031180-1 | 10/692.772 |
| | APPLICANT | |
| | Mirzazimi, et al | |
| LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT(S) INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary) | FILING DATE | GROUP ART UNIT |
| | 10/24/2003 | 1763 |

| REFERENCE DESIGNATION | | | U.S. PATENT DOCUMENTS | | | | |
|-----------------------|----|--------------------|-----------------------|------------------------------------|-------|----------|----------------------------------|
| EXAMINER INITIAL | | DOCUMENT NUMBER | DATE | NAME | CLASS | Subclass | Filing Date if Appropriate |
| LV | A1 | 5,624,529 | 4/29/1997 | Dry Etching Method for Shul et al. | | | |
| | | | | Compound Semiconductors | | | |
| LV | A2 | 2003/066817 | 4/10/2003 | Tanabe, et al Dry Etching Method | | | |
| | | | | and Apparatus | | | |
| | A3 | | | | | | |

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

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|----|----|--|--|--|--|--|--|
| LV | C1 | Kim DW, et al - "A Study of GaN Etching Characteristics Using HBr-Based Inductively Coupled Plasmas" Solid State Electronics, Elsevier Science Publishers, Barking, GB | | | | | |
| LV | C2 | Pearson SJ, et al - "Dry Etching Characteristics of III-V Semiconductors in Microwave BCL3 Discharges" Plasma Chemistry and Plasma Processing, Plenum Press, New York, US - vol. 13, no. 2, June 1, 1993 | | | | | |
| LV | C3 | Lee, et al - "Reactive Ion Etching of Vertical GaN Mesas by the Addition of Cl14 to BC13/H2/Ar Inductively Coupled Plasmas" - Semiconductor Science and Technology, 10P, Bristol, GB, vol. 16, no. 6, June 2001 | | | | | |
| LV | C4 | Langer JP, et al - "Electron Cyclotron Resonance Plasma Etching of GaSb in Cl2/BC13/CH4/Ar/H2 at Room Temperature" Journal of Vacuum Science & Technology B: Microelectronics Processing and Phenomena, American Vacuum Society, New York, NY, US - vol. 21, no. 4, July 2003. | | | | | |
| | C5 | | | | | | |

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|---|-----------------------------|
| EXAMINER: /Lan Vinh/ | DATE CONSIDERED: 06/30/2006 |
| EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant(s). | |